



PATENT
0033-0701P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: NAKABAYASHI et al. Conf.: 1937
Appl. No.: 09/813,152 Group: 1765
Filed: March 21, 2001 Examiner: L. VINH
For: SUSCEPTOR AND SURFACE PROCESSING METHOD

TC 1720 MAIL ROOM

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REPLY TO RESTRICTION REQUIREMENT

Assistant Commissioner for Patents
Washington, DC 20231

February 19, 2003
(Day after Federal Holiday)

Sir:

In reply to the Restriction Requirement dated January 15, 2003, the following remarks are respectfully submitted in connection with the above-identified application.

REMARKS

Claims 1-10 are pending in the present application.

The Examiner has required election in the present application between:

Group I, claims 1, drawn to a susceptor/a device/a product, classified in class 156, subclass 345; and

Group II, claims 2-10, drawn to a method of etching the surface of the susceptor, classified in class 438, subclass 745.